

Docket No.: 50099-183

PATENT

Jc986 U.S. PTO
09/973182
10/10/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Seiichiro OKUDA, et al.

Serial No.:

Group Art Unit:

Filed: October 10, 2001

Examiner:

For: SUBSTRATE PROCESSING APPARATUS

CLAIM OF PRIORITY

Commissioner for Patents
Washington, DC 20231

Sir:

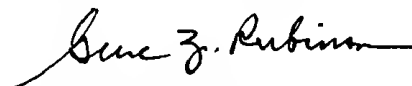
In accordance with the provisions of 35 U.S.C. 119, Applicants hereby claim the priority of:

Japanese Patent Application No. 2000-313496, filed October 13, 2000

A Certified copy will be filed in due course.

Respectfully submitted,

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